



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Patent Application of

Si Yi Li et al.

Application No.: 09/820,695

Filing Date: March 30, 2001

Title: METHOD OF PLASMA ETCHING
LOW-K DIELECTRIC MATERIALS

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) Group Art Unit: 1763
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) Examiner: ALLAN W OLSEN
)
) Confirmation No.: 4162
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PETITION FOR EXTENSION OF TIME

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

The following extension of time is requested to: to extend the respond period of filing the Appeal Brief for

Two Months to May 23, 2007

☒ \$ 450

☐ \$ 225

- ☐ The shortened statutory period has been reset by an Advisory Action dated _____.
- ☐ An Extension fee in the amount of _____ is enclosed.
- ☐ Charge _____ to Deposit Account No. 02-4800.
- ☒ Charge \$ 450 to credit card. Form PTO-2038 is attached.

The Director is hereby authorized to charge any appropriate fees under 37 C.F.R. §§1.16, 1.17 and 1.21 that may be required by this paper, and to credit any overpayment, to Deposit Account No. 02-4800. This paper is submitted in duplicate.

Respectfully submitted,

BUCHANAN INGERSOLL & ROONEY PC

Date: May 23, 2007

By:

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